Inventor: Yuan Huang et al.

Title: Method for Forming Silicon Film with Changing Grain Size by
Thermal Process
Application No. ______
Attorney Docket No. MXIC 1532-1

. 1/6

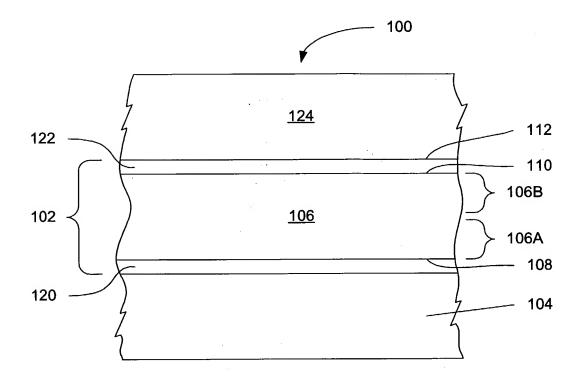


FIG. 1

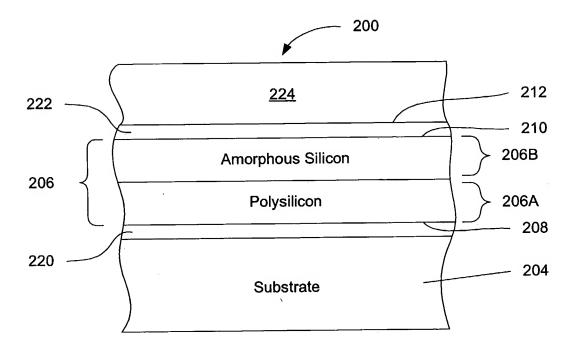


FIG. 2

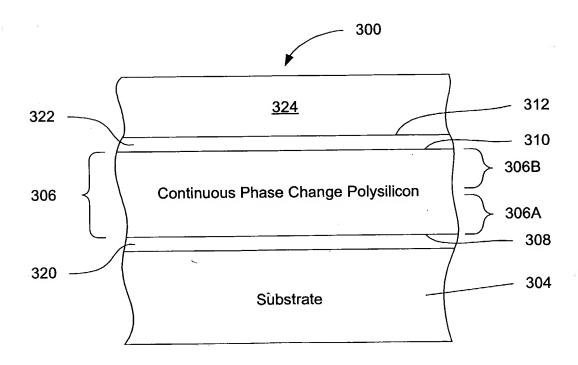


FIG. 3

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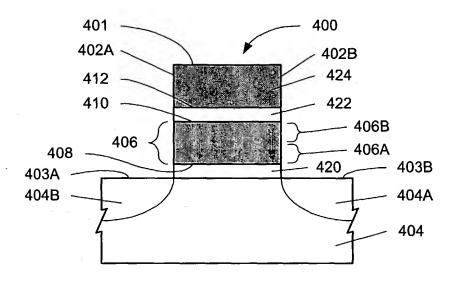


FIG. 4

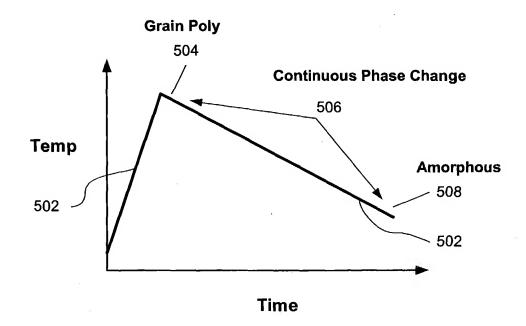


FIG. 5

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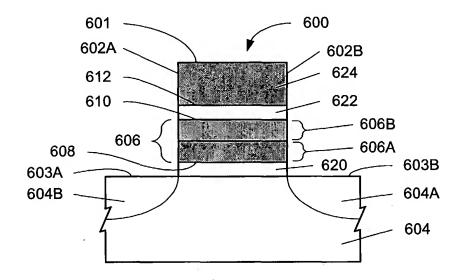


FIG. 6

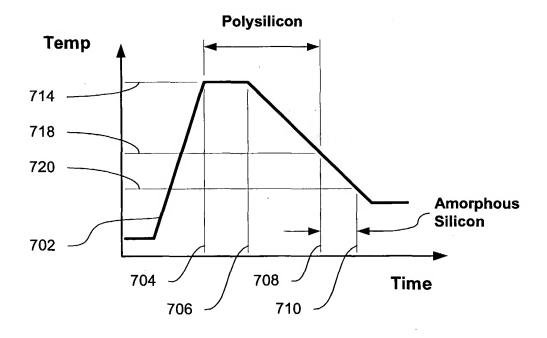


FIG. 7

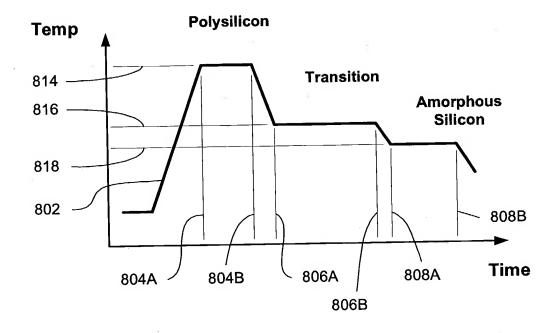


FIG. 8

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